



Open menu



Highest resolution,
imaging & property mapping

LEARN MORE



Home

News

Nano Databases

Nano Business

Nano Jobs

Resources

Introduction to Nanotechnology

The Most
Accurate
AFM

Ellipsometry Service

Measurement Service 4 Film/Coating
Thickness. & Optical Constants



Nanotechnology Spotlight

Behind the buzz and beyond the hype:
Our Nanowerk-exclusive feature articles

Search

Next-Level
Nanotechnology Tools

PVD Wafer Services

PVD Thin film wafer services Thin film Silicon



Posted: Oct 27, 2006

Novel method simplifies large-scale nanofabrication process

(Nanowerk Spotlight) As scientific interests and engineering applications delve down to the nanometer scale, there is a strong need to fabricate nanostructures with good regularity and controllability of their pattern, size, and shape. Furthermore, the nanostructures are useful in many applications only if they cover a relatively large sample area and the manufacturing cost is reasonable. Researchers at UCLA have now achieved a breakthrough by developing a simple but efficient fabrication method to produce well-regulated silicon nanostructures over a large sample area with excellent control of their pattern, size, and shape. Affordable surfaces with well-controlled nanostructures over a large area open new applications not only in electronics but also

in the physical world through their unique properties originating from their nanoscale geometry.

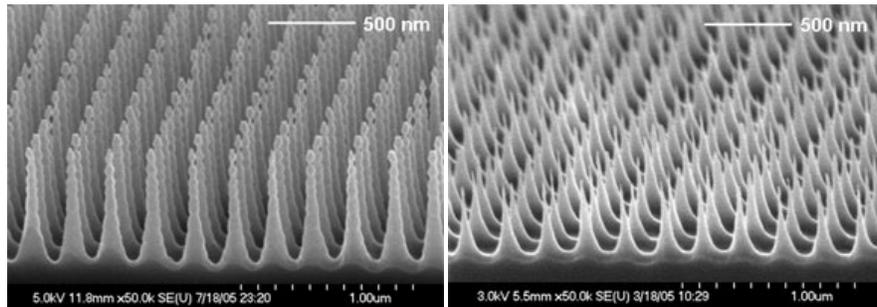
While several nanoscale patterning techniques are known and available, most of them involve a serial method such as e-beam lithography inapt for covering areas larger than square millimeters. X-ray lithography is parallel and can pattern a large area, but it is too expensive for most applications. Soft lithography-based fabrication, such as nanoimprinting, replicates patterns in a parallel fashion, but it still needs a master mold first manufactured by e-beam or X-ray lithography. Most non-lithographic methods, such as the use of nanotemplates (e.g., copolymers) or the direct growth of nanostructures (e.g., carbon nanotubes), lack the regularity some applications demand over a large area.

Professor Chang-Jin "CJ" Kim and Chang-Hwan Choi from the Micro- and Nanomanufacturing Laboratory at UCLA's [Mechanical and Aerospace Engineering Department](#), came up with a simple but efficient nanofabrication method to create a dense (nanoscale pitch) array of silicon nanostructures (post and grate) of varying height and shape over a large sample area.

Choi explained their findings to Nanowerk: "We coupled interference lithography with [deep reactive ion etching](#) (DRIE), which is a new nanofabrication approach. Interference lithography is currently considered the most efficient way to make submicron-scale periodic patterns over a large area (up to a meter range, reportedly) with excellent control of pattern regularity. Although DRIE has rarely been used to construct nanostructures because the rippling of sidewalls (so-called 'scalloping effect') is too prominent on the nanoscale, we demonstrated that a common DRIE process could produce well-defined tall nanostructures by controlling etching parameters and even tailor the sidewall profiles of the nanostructures as desired."

The new idea of utilizing the DRIE and the nanoscale scalloping effect inherent in it for nanostructure fabrication not only simplified nanofabrication processes but also enabled three-dimensional nanofabrication with a single lithography and etching step.

"If conventional techniques were used to create the structures similar to ours, multiple lithography steps with precise alignment or a lithography step with multi-layer resists (or multi-step post processes) would have been required" says Choi. "The three-dimensional sidewall profile control further enabled a simple way to subsequently sharpen the nanostructures' tips for pointed sharp-tip nanostructures."



(Left) SEM image of a silicon nanopost structure with the three-dimensional variation of the sidewall profile enabled by modulating the nanoscalloping effect in DRIE. (Right) SEM image of silicon nanostructures nanostructures with sharp tips. Tips of nanostructures whose sidewall profiles were designed to be positively tapered and scalloping-free were subsequently sharpened by thermal oxidation followed by oxide etching, and measure less than 5 nm in tip apex radius of curvature. (Source: Chang-Hwan Choi)

The researchers point out that three-dimensional nanostructures such as a re-entrant sidewall profile (such re-entrant sidewall profiles are not shown here but can be seen in their recent report "[Fabrication of a dense array of tall nanostructures over a large sample area with sidewall profile and tip sharpness control](#)" in the October 6, 2006 online edition of *Nanotechnology*.) are desirable in several applications, such as T-gates for microwave transistors, wave modulators for nano-optics, and various nanoelectromechanical systems (NEMS). For a given void fraction under the surface, nanostructures with a re-entrant profile provide less open and more flat area on the surface than simple profiles do. Another use of such a re-entrant profile would be to produce monolithic nanochannels by sealing the top of the nanograte patterns with a thin-film deposition. Well-regulated sharp-tip nanostructures covering a large pattern area, especially needle-like nanopost patterns, commonly are of interest in such electronic applications as field emitter structures. The simple but efficient method of sharp-tip nanofabrication will also facilitate the

design and fabrication of high-aspect-ratio scanning probe tips.

"Our first application opened by the densely-populated nanostructures over a large sample area was to fabricate nanopatterned superhydrophobic surfaces of good mechanical robustness and geometric regularity, compared with the micropatterned or irregularly-patterned (e.g., chemically-formed or polymer-roughened) superhydrophobic surfaces that have so far been reported" says Choi. "The nanostructures with the regular pitch and shape allowed us to study the effect of nanostructure geometries on the surface superhydrophobicity."

Especially, slender and tall sharp-tip nanostructures with the nanometer-scale dense pitch made the microfluidic application to the friction reduction in liquid flow more practical and beneficial, tolerating highly pressurized flows without losing the superhydrophobicity. These findings were reported in *Physical Review Letters* ("[Large Slip of Aqueous Liquid Flow over a Nanoengineered Superhydrophobic Surface](#)") and *Physics of Fluids* ("[Effective slip and friction reduction in nanogated superhydrophobic microchannels](#)").

Choi notes that the well-regulated nanotopographical properties of their nanostructures enabled another possibility for exploration, which is cell biology. Although several cell behaviors over various surface topographies have been studied with micro- and nanostructured surfaces, there is little information on the cell reactions to the well-ordered nanostructured surfaces.

"Our well-ordered nanostructures provided a unique opportunity, whereby the well-defined surface structures on the nanoscale could elucidate many aspects of the nanobiology of the cell, including the effect of surface three-dimensionality (i.e., three-dimensional nanotopography) on cell proliferation, morphology, alignment, and adhesion, whose understanding will further be utilized for cell and tissue engineering applications" he says. (Further details can be found in a recent paper "[Cell Adhesions on Nanoturf Surfaces](#)" which appeared in *Proceedings of the 19th International Conference on Micro Electro Mechanical Systems*, Istanbul, Turkey).

Currently, the nanostructured surface fabricated at [Kim's lab](#) is made out of a silicon substrate. Well-regulated nanostructures of other materials such as soft polymers are also desired for certain applications, e.g., novel biomaterials for tissue engineering. Nanopatterned soft polymer materials will also have superiority to rigid solid nanostructured surfaces in respect that they can create a flexible nanostructured surface and be applied on curved bodies.

The DRIE is not suitable to etch the other material than silicon so that new nanofabrication methods for the flexible soft materials may need to be sought in the future.

"To retain the advantage of the current method – good control of pattern, size, and shape – our well-regulated silicon nanostructures can be used as mold or master structures to be replicated on the soft materials, which is now investigated in our lab" Choi concludes.

By [Michael Berger](#), Copyright Nanowerk LLC

0 Comments

Nanowerk

 Login ▾

Sort by Newest ▾

Share  Favorite 



Start the discussion...

Be the first to comment.

 Subscribe

 Add Disqus to your site

 Privacy

Subscribe! Receive a convenient email notification whenever a new [Nanowerk Nanotechnology Spotlight](#) posts.

Become a Spotlight guest author! Have you just published a scientific paper or have other exciting developments to share with the nanotechnology community? [Here is how to publish on nanowerk.com.](#)

Precision Nanomaterials Printer



Nanotechnology Spotlights



Most recent:

A one-pot strategy for synthesizing high-performance transparent conducting oxide nanocrystal inks

Posted: Jan 09, 2015

A risk-ranking tool for nanomaterials used by the militarySingle-pot electrolytic synthesis of hydrogen and carbon fuels

Posted: Jan 06, 2015

Posted: Jan 05, 2015

Silky substrate makes flexible solar cells biocompatibleShapeshifting metal nanoparticles eating tracks in graphene

Posted: Dec 30, 2014

Posted: Dec 19, 2014

Carbon nanotubes enable new way of sound generationA nanoelectromechanosensing approach to detect cancerous transformation of single cells

Posted: Dec 18, 2014

Posted: Dec 17, 2014

How the insurance market perceives nanotechnology risksUltraflat transfer method for graphene surface force balance

Posted: Dec 16, 2014

Posted: Dec 10, 2014

Thermotherapy for pain management with a smart thermal patchLeverage nanotechnology to speed up the energy transition

Posted: Dec 09, 2014

Posted: Dec 05, 2014

Unlocking the potential of graphenes - functionalisation via plasma

Posted: Dec 04, 2014

European Parliament agrees on moratorium on nanofoods and on a new legal definition of engineered nanomaterials

Posted: Dec 03, 2014

Superstable copper nanowire stretchable conductors3D printed nanostructures made entirely of graphene

Posted: Dec 02, 2014

Posted: Nov 27, 2014

Protecting satellite electronics with reinforced carbon nanotube filmsSurface state engineering to achieve white LEDs with carbon nanomaterials

Posted: Nov 26, 2014

Posted: Nov 25, 2014

Foldable capacitive touch pad printed with silver nanowire inkFood chemistry synthesis of copper nanowires with chocolate-like aroma

Posted: Nov 24, 2014

Posted: Nov 21, 2014

Nanotechnology in the 'green' economy - opportunities and risksGraphene electrodes for simultaneous electrophysiology and neuroimaging

Posted: Nov 18, 2014

Posted: Nov 13, 2014

Nanoimprint lithography for the fabrication of efficient low band gap polymer solar cellsOptical transmittance of multilayer graphene films

Posted: Nov 12, 2014

Posted: Nov 11, 2014

Fully 3D-printed quantum dot LEDsThe photothermal response of nano-devices: Electrons rolling 'uphill' in a carbon nanotube

Posted: Nov 05, 2014

Posted: Nov 04, 2014

Understanding springs at the nanoscale: a step towards nanorobots

Posted: Oct 31, 2014

2D molybdenum disulfide: a promising new optical material for ultra-fast photonicsA nano-thermodynamic look at gold-copper alloys

Posted: Oct 30, 2014

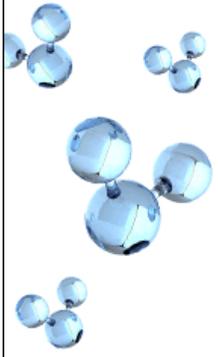
Posted: Oct 29, 2014

[READ MORE SPOTLIGHTS](#)





*Making
water go
further
using
natural
cellular
processes for
purification.*

A cluster of blue and white spheres representing water molecules, arranged in a non-crystalline structure.

iⁿgenuity lab
nature | nano | networks



LEARN ABOUT ADVANCES
IN WATER RECLAMATION





Follow @Nanowerk

[Nanotechnology Home](#) | [Privacy](#) | [Terms of use](#) | [Contact us](#) | [What is Nanotechnology?](#)
| [Sitemap](#) | [Advertise](#) | [Submit news](#)

The contents of this site are copyright ©2015 Nanowerk. All Rights Reserved